



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application Serial No. ....09/805,620  
Confirmation No. ....3004  
Filing Date ..... March 13, 2001  
Inventor..... Craig M. Carpenter  
Assignee ..... Micron Technology, Inc.  
Group Art Unit.....1762  
Examiner ..... E. Fuller  
Attorney's Docket No. ....MI22-1563  
Customer No.....021567  
Title: Chemical Vapor Deposition Methods (Amended)

**RESPONSE TO MARCH 10, 2004 OFFICE ACTION**

To: Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

From: Satheesh Karra (Tel. 509-624-4276; Fax 509-838-3424)  
Wells St. John P.S.  
601 W. First Avenue, Suite 1300  
Spokane, WA 99201-3828

**AMENDMENTS**

**Amendments to the Title** begin on page 2 of this paper.

**Amendments to the Specification** begin on page 3 of this paper.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 4 of this paper.

**Remarks** begin on page 12 of this paper.

**EV 372452900**

**Amendments to the Title**

Please amend the title as follows:

Chemical Vapor Deposition Apparatuses and Deposition Methods